

Application No.: 10/763,727
Amendment dated: June 6, 2005
Reply to Non-Compliant Amendment dated: May 5, 2005

AMENDMENTS TO THE SPECIFICATION

Please amend the title as follows:

SYSTEM ~~AND METHOD~~ FOR PREVENTING OPERATIONAL AND
MANUFACTURING IMPERFECTIONS IN PIEZOELECTRIC MICRO-ACTUATORS

Please add the following paragraphs to the specification after paragraph [0011].

[0011a] Figures 8a-b provides a cross-section of the micro-actuator arms with the micro-actuators unseparated and a cross-section of a micro-actuator arm after micro-actuator separation and ending with PZT layer application under principles of the present invention.

[0011b] Figure 9 provides a cross-section of a finger of a micro-actuator under principles of the present invention.

Please amend the Specification as follows:

[0015] Figure 6 provides a cross-section of the micro-actuator arms with the micro-actuators unseparated and a cross-section of a micro-actuator arm after micro-actuator separation.

Figure 6a illustrates a cross-section 604 of a portion 602 of a micro-actuator block structure.

The cross-section 604 illustrates alternating layers 628 of conductive material 622 and PZT

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(insulating) material 624 applied to the micro-actuator. Figure 6b illustrates a cross-section 608 of a micro-actuator arm 606 after separating the micro-actuator 610 from others. Separation 602 may be performed in one embodiment by mechanical means (*e.g.*, a rotating wheel blade or a straight edge knife). Other embodiments involve electrical means for micro-actuator separation (*e.g.*, electric sputtering or ion milling). Further, chemical means may be used (*e.g.*, chemical vapor deposition (CVD)). Note that the sides 612 of the micro-actuator arm (finger) 606 expose the piezoelectric layers, including the electrically-conductive layers 622.